

Inventor: Michael T. Andreas

Title: Method of Processing a Semiconductor Substrate, Method of Cleaning Registration Alignment Markings Formed on a Semiconductor Substrate, and Post-CMP Cleaning Process

Assignee: Micron Technology, Inc.

INFORMATION DISCLOSURE STATEMENT

References -- See Attached Form PTO-1449

The attached form PTO-1449 is submitted in compliance with 37 CFR § 1.56. Copies of the cited art are included. No admission is made regarding whether all the submitted references are prior art.

Respectfully submitted,

Dated: 18 Sep 2003

Attorney: _____

James E. Lake
Reg. No. 44,854

Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. MI22-2335		SERIAL NO. Unknown	
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT: Michael T. Andreas			
				FILING DATE Filed Herewith		GROUP Unknown	

U.S. PATENT DOCUMENTS							
*Examiner's Initials		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA						
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	AG						
	AH						
	AI						

FOREIGN PATENT DOCUMENTS							
		Document Number	Date	Country	Class	Subclass	Translation
							Yes No
	AJ						
	AK						
	AL						

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)			
AM		S. Wolf & R. Tauber, SILICON PROCESSING FOR THE VLSI ERA, VOL. 1: PROCESS TECHNOLOGY , pp. 137 and	
		761-764 (2000).	
AN			
AO			
EXAMINER		DATE CONSIDERED	

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.